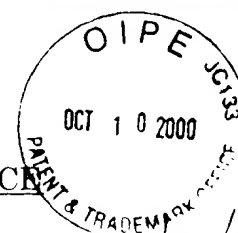




Gr. 1765 A



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In Re Application of:

Inventor: David Evans

Serial No.: 09/270,606

Filed: March 17, 1999

Title: METHOD FOR
MODIFICATION OF
POLISHING
PATTERN
DEPENDENCE IN
CHEMICAL
MECHANICAL
POLISHING

PATENT APPLICATION

Group No. 1765

Examiner: M. Anderson

TECHNOLOGY CENTER 1700

RECEIVED

Box Fee Amendment
Assistant Commissioner for Patents
Washington, DC 20231

RESPONSE UNDER 37 C.F.R. § 1.111

Sir:

This Response is an amendment responsive to an Office
Action dated March 27, 2000.

Please amend the above-identified application as follows:

IN THE SPECIFICATION:

On page 4, at line 2, please delete the word "greater" and
insert therefor the word --lower--.